

Supplementary Information

A Nanoimprinted Artificial Engram Device

*Xuesong Li^{a,b}, Pan Zeng^a, Feilong Wang^a, Dai Zhang^{a,b}, Yi Zhou^c,
Rongqing Liang^a, Qiongrong Ou^a, Xiang Wu^c, Shuyu Zhang^{a,*}*

^a Institute for Electric Light Sources, Department of Light Sources and Illuminating Engineering, School of Information Science and Technology, Fudan University, Shanghai 200433, P. R. China

^b Institute of Future Lighting, Academy for Engineering and Technology, Fudan University, Shanghai 200433, P. R. China

^c Key Laboratory of Micro and Nano Photonic Structures (Ministry of Education), Department of Optical Science and Engineering, School of Information Science and Technology, Shanghai Engineering Research Centre of Ultra Precision Optical Manufacturing, Fudan University, Shanghai 200433, China

*Email address: zhangshuyu@fudan.edu.cn

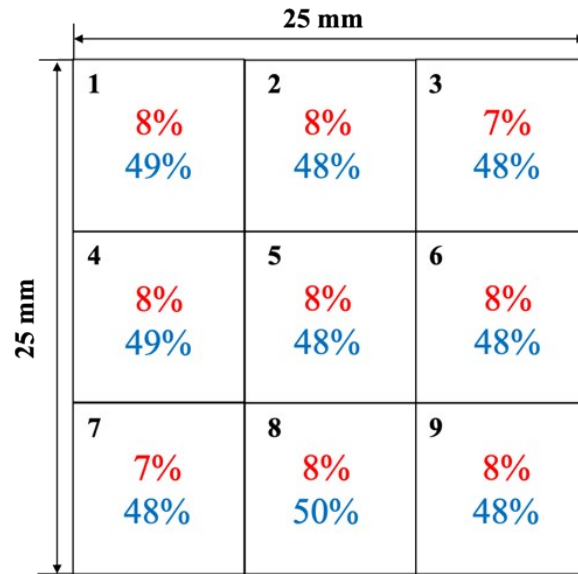


Fig. S1 The relative diffraction efficiencies measured at different locations after heating (120 °C for 30 seconds) and UV irradiation (100 mW/cm² for 3 hours). The device area is divided into a 3 by 3 grid. the relative diffraction efficiencies measured at different locations range from 7% to 8% after heating (marked in red) and from 48% to 50% after UV irradiation (marked in blue). The standard deviation is less than 0.7%. A good device uniformity is demonstrated.

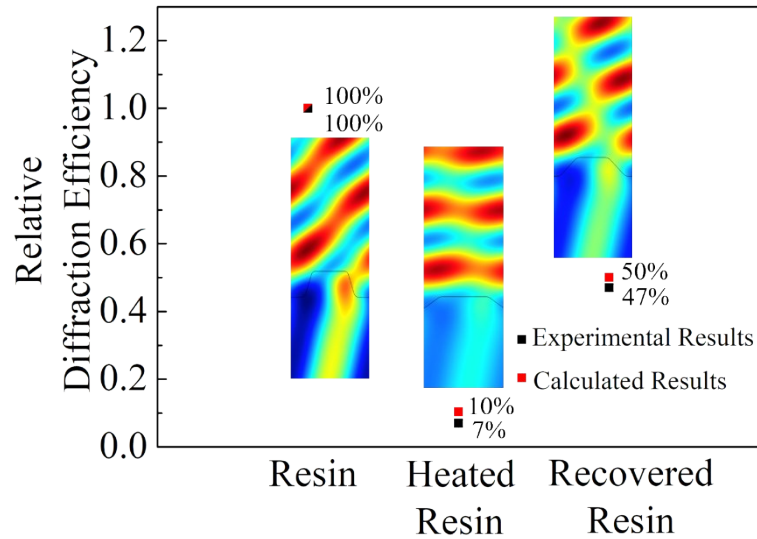


Fig. S2 Experimental (black solid squares) and calculated (red solid squares) relative diffraction efficiencies of a pristine SPC-347 UVCR grating, the grating after the heating treatment (120 °C for 30 seconds) and the heat-treated grating after the natural restoring process (2 days). The inset figures show the corresponding spatial distribution of the electromagnetic field $|E|^2$ in a periodic unit structure for a 532 nm plane wave at an incident angle of 25° to the surface normal of the device. The calculation was carried out using a finite element method using a commercial software COMSOL Multiphysics 5.2a.